

### **Amendment to the claims**

1. (Currently cancelled)
2. (Currently cancelled).
3. (Previously Cancelled).
4. (Currently Cancelled)
5. (Currently Cancelled)
6. (Currently Cancelled)
7. (Currently Cancelled)

8. (Allowed) A method of manufacturing a filter arrangement, which comprises a substrate and provided thereon a bandpass filter of bulk acoustic wave resonators and a notch filter, by which method

- a second electrode (5), a piezoelectric layer (4), and a first electrode (3) are provided sequentially on a carrier layer with said second electrode (5) adjoining said carrier layer, and are structured such that at least one resonator unit, a capacitor, and an inductance are created,

- a reflection element (2) is deposited on those portions of the first electrode (3) which belong to the resonator unit,

- a substrate (1) is fastened on said first electrode (3), and the carrier layer is removed.

9. (Previously Cancelled).
10. (Previously Cancelled).
11. (Previously Cancelled).
12. (Previously Cancelled).
13. (Allowed) A filter arrangement as claimed in claim 1, characterized in that the

bandpass filter and the notch filter are thin-film filters.

14. (Allowed) The method of claim 8, wherein said carrier layer consist of a ceramic material, a ceramic material with a planarizing layer of glass, a glass-ceramic material, silicon, GaAs or sapphire.

15. (Previously Cancelled).

16. (Previously Cancelled).